CLAIMS

[Claim 1] A method comprising:

cleaning an optical sensor head by supplying a rinsing liquid into a through-hole formed in a polishing pad on a polishing table before or after polishing of a substrate with use of slurry is performed, the optical sensor head being located below the through-hole; and

discharging the rinsing liquid from the through-hole through a drain line,

wherein the rinsing liquid is supplied into the through-hole from a polishing-pad cleaning nozzle arranged above the polishing pad.

[Claim 2] A method comprising:

cleaning an optical sensor head by emitting a rinsing liquid toward a lower surface of a polishing-pad cleaning nozzle arranged above a polishing pad, and supplying the rinsing liquid that has fallen from the lower surface of the polishing-pad cleaning nozzle into a through-hole formed in the polishing pad on a polishing table before or after polishing of a substrate with use of slurry is performed, the optical sensor head being located below the through-hole; and

discharging the rinsing liquid from the through-hole through a drain line.

[Claim 3] The method according to claim 1 or 2, wherein the drain line is coupled to a drain pump configured to suck the rinsing liquid from the through-hole.